## PROCEEDINGS OF SPIE

# **Applied Optical Metrology III**

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James D. Trolinger
Editors

13–15 August 2019 San Diego, California, United States

Sponsored and Published by SPIE

**Volume 11102** 

Proceedings of SPIE 0277-786X, V. 11102

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Applied Optical Metrology III, edited by Erik Novak, James D. Trolinger, Proc. of SPIE Vol. 11102, 1110201 · © 2019 SPIE · CCC code: 0277-786X/19/\$21 · doi: 10.1117/12.2551001

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Please use the following format to cite material from these proceedings:

Author(s), "Title of Paper," in Applied Optical Metrology III, edited by Erik Novak, James D. Trolinger, Proceedings of SPIE Vol. 11102 (SPIE, Bellingham, WA, 2019) Seven-digit Article CID Number.

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510628977

ISBN: 9781510628984 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445

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